

The 123rd Microoptics Meeting
Ultra-precision Microoptics

Sponsored by Microoptics Group, Optical Society of Japan, JSAP



Date: March 1, 2012 (Thu.) 10:00-17:00

Location: Rm. 4201, Bld. 4, Takanawa-Campus, Tokai Univ.

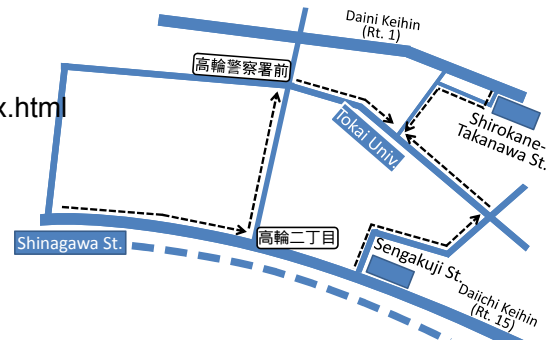
2-3-23 Takanawa, Minato-ku, Tokyo 108-8619

<http://www.u-tokai.ac.jp/about/campus/takanawa/index.html>

Access: 8 min. walk from Sirokane-Takanawa St.

10 min. walk from Sengakuji St.

18 min. walk from Shinagawa St.



Program

- 10:00 ~ 10:10 Opening Remarks
- 10:10 ~ 11:40 Prospects of precise time comparison with optical lattice clocks
Hidetoshi Katori (Univ. Tokyo)
- 10:40 ~ 11:10 Optical comb, the most precision ruler for time, space, and frequency
Kaoru Minoshima, Guan hao Wu, Kaoru Arai, Mariko Kajima, Hajime Inaba (AIST)
- 11:10 ~ 11:40 Investigation of local optical response using X-ray parametric down-conversion
Kenji Tamasaku (Riken, PRESTO-JST)
- 11:40 ~ 12:10 3D atomic imaging by inverse photoelectron holography
Kouichi Hayashi (Tohoku Univ.)
- 12:10 ~ 13:30 < Lunch Break 80 min. >
- 13:30 ~ 14:00 Development of ultracompact and highly sensitive interferometric displacement sensor using photonic crystals and its application to atomic force microscope
Toshihiko Nakata (Hitachi)
- 14:00 ~ 14:30 Improvement of spatial resolution for photoacoustic imaging to visualize deep structures in living tissues
Yoshihisa Yamaoka, Tetsuro Takamatsu (Kyoto Pref. Univ. Medicine)
- 14:30 ~ 15:00 EUV lithography: Current status and challenges Katsuhiko Murakami (Nikon)
- 15:00 ~ 15:20 < Break 20 min. >
- 15:20 ~ 15:50 Formation of photoresist patterns with nanometric accuracy using plasmon-assisted nanolithography
Kosei Ueno^{1,2}, Hiroaki Misawa¹ (¹Hokkaido Univ., ²PRESTO-JST)
- 15:50 ~ 16:20 Development of high performance anti-reflective coating "SWC" with sub-wavelength structures
Daisuke Sano (Canon)
- 16:20 ~ 16:50 Fabrication of phase-shifted DFB LDs utilizing UV nanoimprint lithography
Masaki Yanagisawa, Yukihiro Tsuji, Hiroyuki Yoshinaga, Naoya Kouno, Naoko Inoue, Kenji Hiratsuka (Sumitomo Electric)
- 16:50 ~ 17:00 Closing Remarks

Registration (On site only): General ¥4,000 / Student, Retiree ¥1,000

Steering Members: Handa (Canon), Shibuya (Tokai Univ.), Sugihara (Tohoku Univ.), Takahashi (Sumitomo Electric), Miyamoto (Tokyo Tech)

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Microoptics Group: Kenichi Iga (General Chair), Kenya Goto (Vice Chair),

Kazuo Kuroda (Organizing Committee Chair), Genichi Hatakoshi (Organizing Committee Vice Chair)

Hirochika Nakajima (Steering Committee Chair), Kiyoshi Yokomori (Steering Committee Vice Chair)

The program of the meeting will be updated in the Web page of Microoptics Group (<http://www.comemoc.com/>)